

# **Characterization of Sputter-Deposited Iridium Oxide Coatings for Medical Implants**

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# Sputter-Deposited Iridium Oxide Coatings

- Why is IrO<sub>x</sub> interesting?
- How can IrO<sub>x</sub> coatings be made?
- Our own sputtering tests.
- Characterization of the coatings.

# Why is IrO<sub>x</sub> interesting?

- excellent compatibility with human body
- "electrode properties":
  - electrical conductivity similar to metal
  - redox reaction between Ir<sup>3+</sup>/Ir<sup>4+</sup> gives reversible electrochromic effect
  - $$\text{H}_x\text{IrO}_2 \rightleftharpoons \text{IrO}_2 + x \text{H}^+ + x \text{e}^- \quad (x \sim 1)$$

colourless  $\rightleftharpoons$  grey
  - transfer of current from electrode to tissue by Faradaic reaction rather than capacitance of Helmholtz electrical double layer  
→ higher current densities

## How can IrO<sub>x</sub> coatings be made?

- sol-gel process

fine IrO<sub>2</sub> powder precipitated from solution of iridium ethoxide by hydrolysis, oxidation and calcination

- thermal oxidation

Ir-C films deposited by evaporation and oxidation in air 10 min / 250 °C

- anodic growth

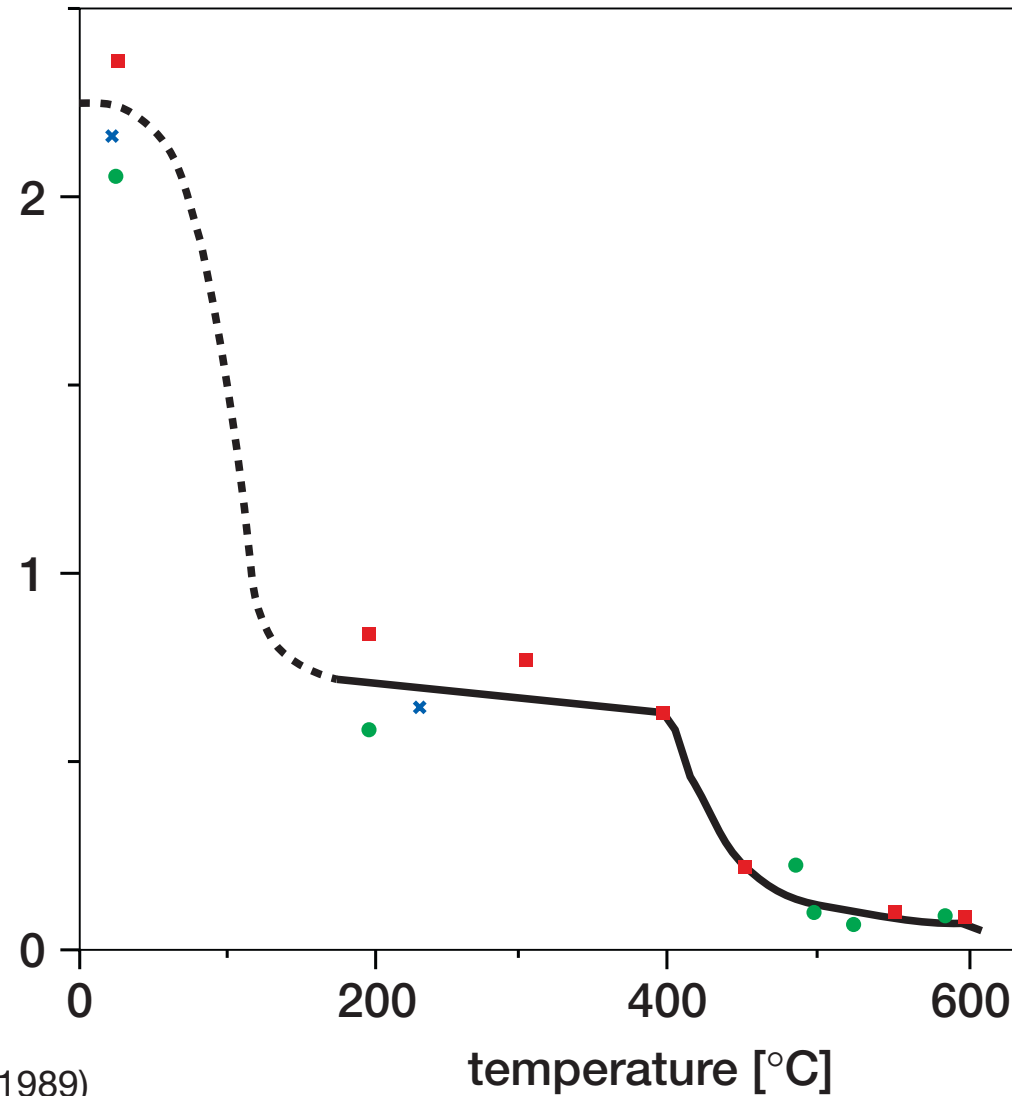
anodic oxidation of Ir metal films in 0.5-M H<sub>2</sub>SO<sub>4</sub> by cycling potential between -0.25 and +1.25 V vs. SCE

- reactive sputtering

sputtering from Ir metal target onto cooled substrates in high purity Ar + O<sub>2</sub>

# Thermal stability of "dry" sputtered $\text{IrO}_x$ films in UHV

ratio O/Ir



(from Sanjinés et al., 1989)

## **Sputtering tests (current investigations)**

- Sputter deposition system with turbo drag pump, magnetron and 10 kW DC power supply
- Ir metal target, >99.9 % purity, solder-bonded to water-cooled backing plate
- Substrates: thin-walled tubes (2mm dia. x 0.15mm wall) mounted on rotating holder; radiation heating
- Atmosphere Ar / O<sub>2</sub>

## Substrates used

- Platinum
- Titanium (grade 2)
- Stainless steel (AISI 316L)
- Stainless steel + adhesion layer

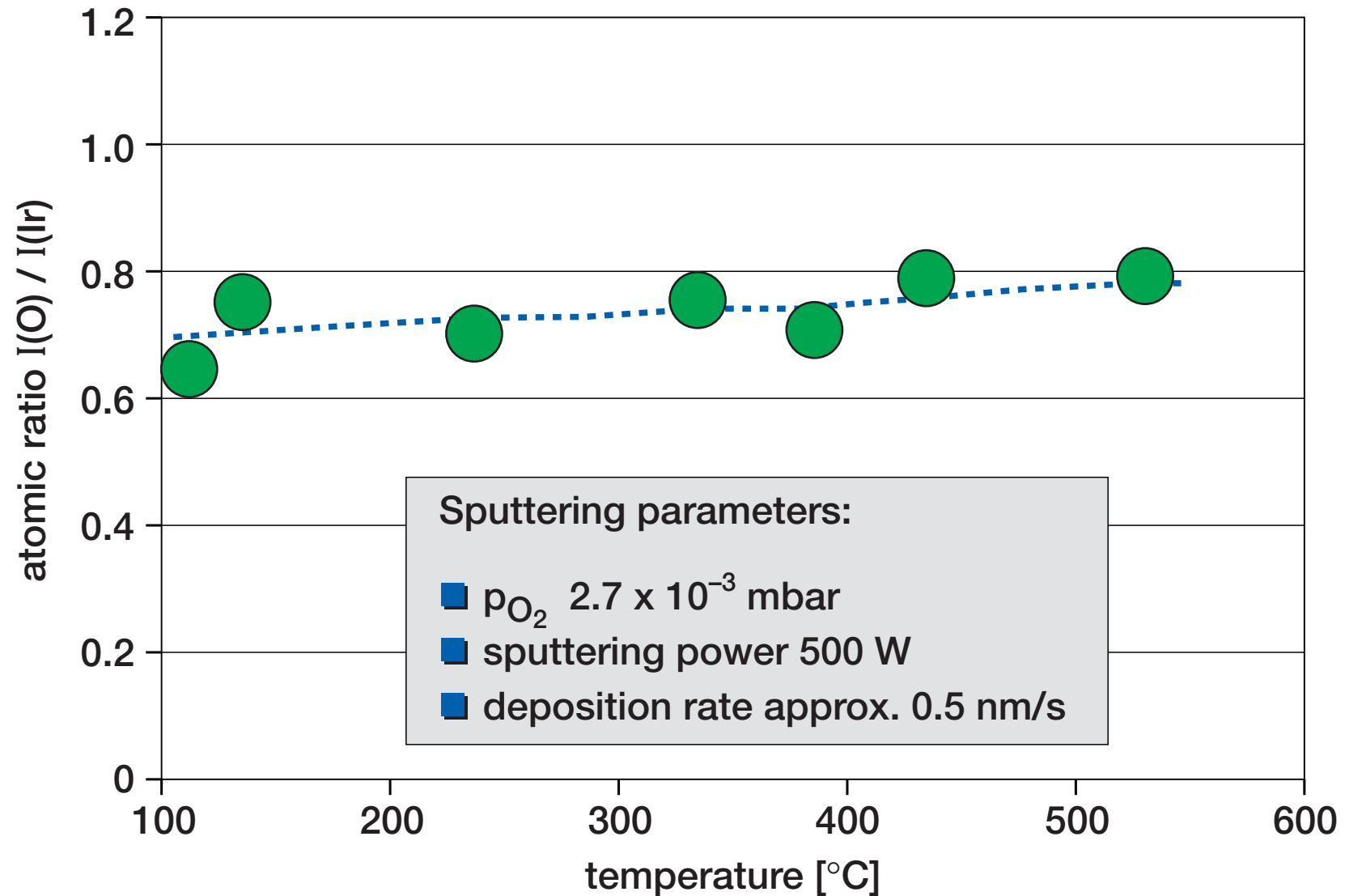
# Sputtering parameters

Test series	Temperature	Power	Oxygen partial pressure
1.	varied	500 W	$2.7 \times 10^{-3}$ mbar
2.	435 °C	varied	$2.7 \times 10^{-3}$ mbar
3.	385 °C	500 W	varied
4.	110 °C	500 W	varied

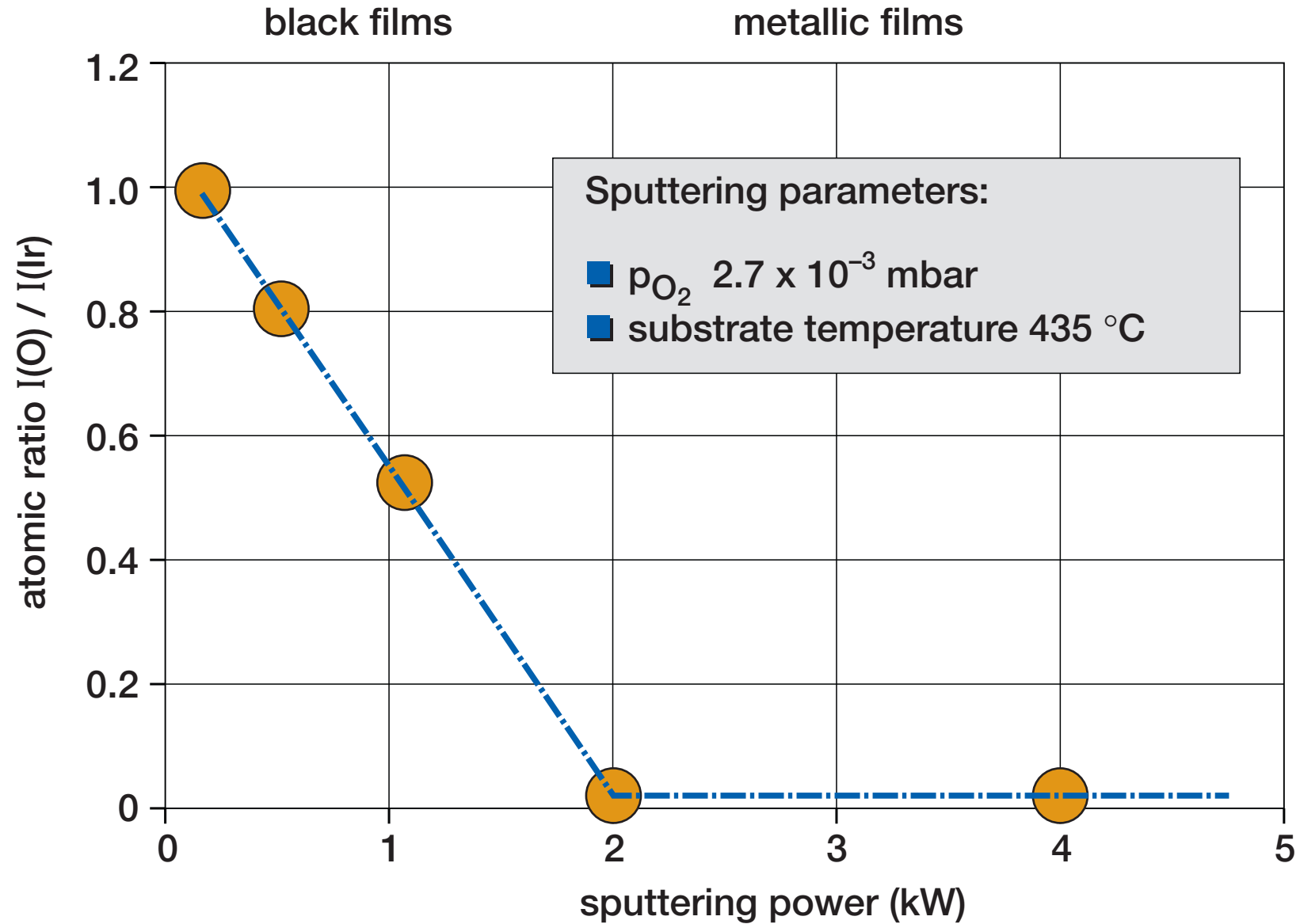
Sputtered energy 300 kJ per test series.

Typical film thickness 0.3  $\mu\text{m}$

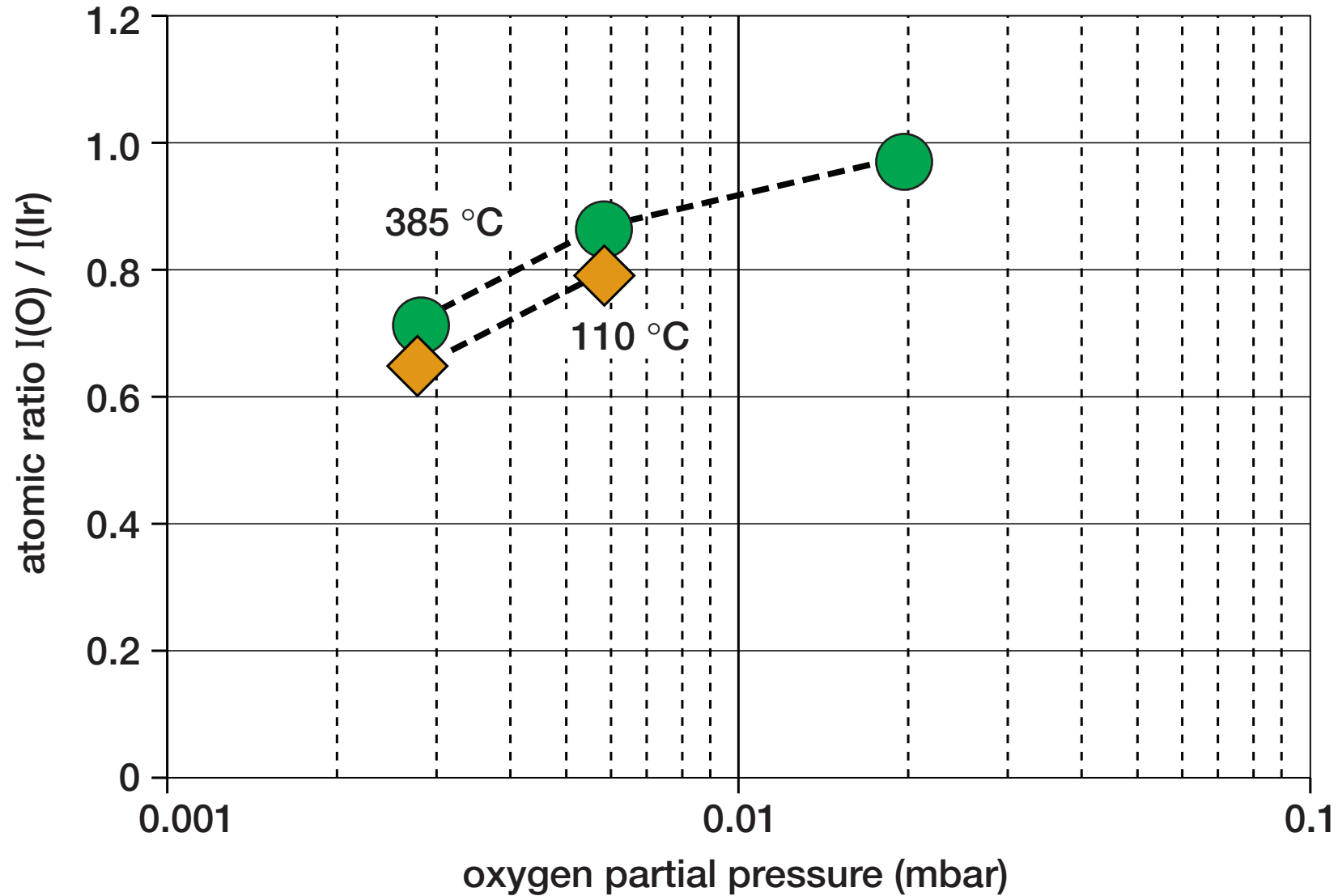
# Influence of substrate temperature on oxygen content



# Influence of sputtering power on oxygen content



# Influence of oxygen partial pressure on oxygen content



# Adherence tests on tube substrates

## 1. Adhesive tape test

→ pass = "good" (fail = "poor")

## 2. Tube squeezed to 0.9 mm

+ ultrasonic bath 20 s

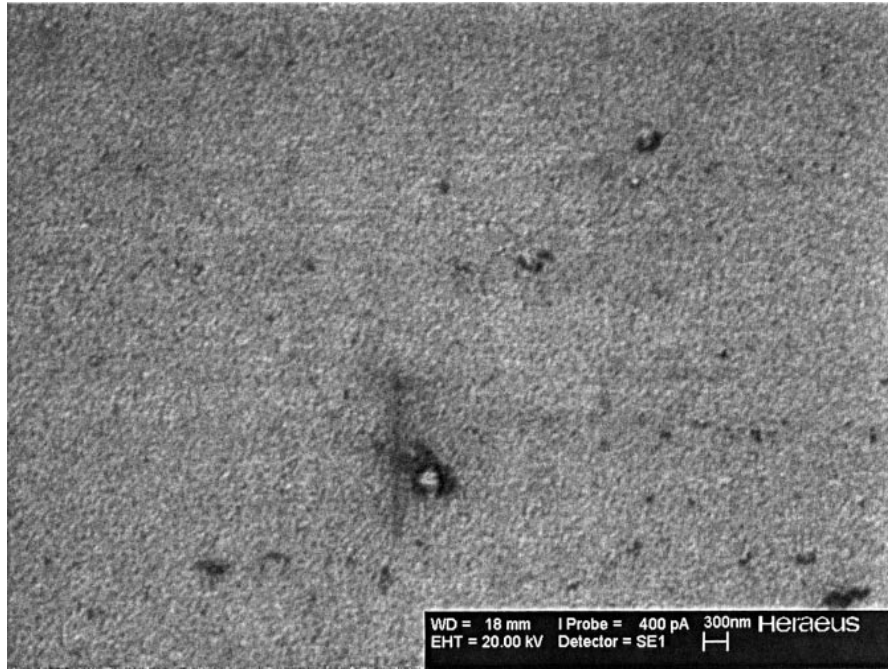
+ examination 20 x

→ pass = "excellent"

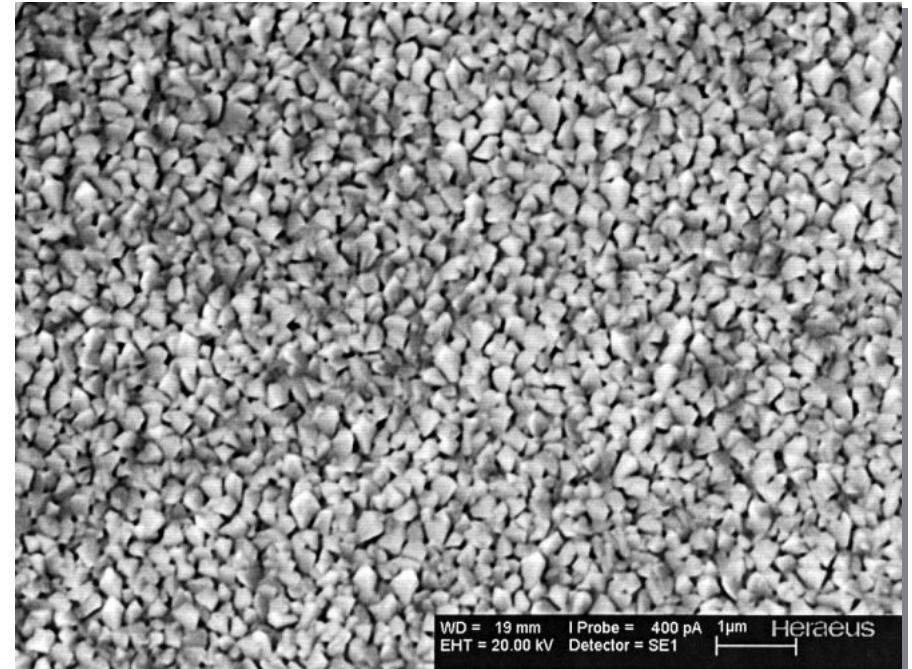
# Adherence test results

Substrate material	Number of samples tested		
	poor	good	excellent
Platinum	0	12	3
Titanium	0	10	5
Stainless steel 316 L	12	3	0
Stainless steel 316 L + adhesion layer	5	6	4

# $\text{IrO}_x$ film morphology



film thickness 0.3  $\mu\text{m}$



film thickness 2  $\mu\text{m}$

## Summary

- Reactive sputtering gives  $\text{IrO}_x$  films of mixed Ir /  $\text{IrO}_2$ .
- Oxygen content nearly constant ( $\text{IrO}_{0.7}$ ) between 120 °C and 535 °C.
- Low growth rate essential for obtaining good Ir /  $\text{IrO}_x$  films but little effect on adherence.
- Adherence "good" to "excellent" on platinum and titanium.
- On stainless steel, metallic adhesion layer necessary.
- Good corrosion stability on stainless steel with adhesion layer.

# X-ray diffraction pattern of IrO<sub>x</sub> coatings

